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Date: March 16, 2005

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

U.S.S.N. 10/686,299

Christenson, et al.

LEAK DETECTION METHOD AND MICRO-
MACHINED DEVICE ASSEMBLY

October 15, 2003

Attorney Docket: DP-310613

ELECTION

Commissioner For Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

This is Applicant's response to the Office Action mailed March 8, 2005, in which the pending claims 1-20 of the above-identified application were subjected to a restriction requirement.

Applicant hereby formally elects, without traverse, to prosecute claims 11-20 of Group II, which are drawn to a micro-machined, classified in class 257, subclass 46. Applicant further requests that claims 1-10 of Group I drawn to method for detection of a leak in a micro-machined device having a device wafer and a capping wafer, classified in class 438, subclass 14 be canceled without prejudice.

Respectfully submitted,

Delphi Technologies, Inc.

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